CLAIMS

1. (Currently Amended) A heterojunction bipolar transistor (HBT), comprising:

successive emitter, base and collector layers, an InP sub-collector layer, and

a thermally conductive InGaAs contact layer between said collector and sub-collector layers,

said contact layer being thin enough to have a lateral conductivity inadequate for it to function by itself as a contact to the collector layer, but functioning as an electrical conductor between said collector and sub-collector layers,

wherein said contact and sub-collector layers extend lateral to said collector layer.

- 2. (Original) The HBT of claim 1, said contact layer having a thickness not greater than about 500 Angstroms.
- 3. (Original) The HBT of claim 2, said contact having a thickness in the approximate range of 100-200 Angstroms.

4. (Cancelled)

- 5. (Currently amended) The HBT of claim $4\,\underline{1}$, further comprising a contact pad on said contact layer lateral to said collector layer for establishing a contact to the collector layer through the contact and sub-collector layers.
- 6. (Original) The HBT of claim 1, wherein at least a portion of said sub-collector layer lateral to said collector layer is electrically insulative to electrically isolate said HBT.

7. (Previously Presented) A heterojunction bipolar transistor (HBT), comprising:

successive emitter, base and collector layers, an InP sub-collector layer, and

a thermally conductive InGaAs contact layer between said collector and sub-collector layers,

wherein at least a portion of said sub-collector layer lateral to said collector layer is electrically insulative to electrically isolate said HBT, and said sub-collector layer extends laterally beyond said contact layer and said insulative portion of the sub-collector layer is lateral to said contact layer.

- 8. (Original) The HBT of claim 6, said insulative portion of the sub-collector layer including implanted ions and associated trapped conductors.
- 9. (Currently Amended) A double heterojuntion bipolar transistor (DHBT), comprising;

an InP or InAlAs emitter,

an InGaAs base,

an InP or InGaAs collector,

an InP sub-collector, and

an InGaAs contact layer between said collector and sub-collector which establishes, together with the sub-collector, a low resistance contact to the collector, said contact layer being thin enough to provide a substantially higher thermal conduction path between said collector and sub-collector than would bulk InGaAs, and to have a lateral conductivity inadequate for it to function by itself as a contact to the collector,

wherein said contact layer and sub-collector extend lateral to said collector.

- 10. (Original) The DHBT of claim 9, said contact layer having a thickness not greater than about 500 Angstronms.
- 11. (Original) The DHBT of claim 10, said contact layer having a thickness in the approximate range of 100-200 Angstroms.
- 12. (Original) The DHBT of claim 9, wherein said contact layer in doped N+.

13. (Cancelled)

- 14. (Currently Amended) The DHBT of claim $\frac{13}{9}$, further comprising a contact pad on said contact layer lateral to said collector.
- 15. (Currently Amended) The DHBT of claim $\frac{13}{9}$, wherein at least a portion of said sub-collector lateral to said collector is electrically insulative to electrically isolate said HBT.
- 16. (Previously Presented) A double heterojuntion bipolar transistor (DHBT), comprising:
 - an InP or InAlAs emitter,
 - an InGaAs base,
 - an InP or InGaAs collector,
 - an InP sub-collector, and
- an InGaAs contact layer between said collector and sub-collector which establishes, together with the sub-collector, a low resistance contact to the collector, said contact layer being thin enough to provide a

Docket No. 01SC027US1

substantially higher thermal conduction path between said

wherein said contact layer and sub-collector extend lateral to said collector, at least a portion of said sub-collector lateral to said collector is electrically insulative to electrically isolate said HBT, said sub-collector extends laterally beyond said contact layer, and said insulative portion of the sub-collector is lateral to said contact layer.

collector and sub-collector than would bulk InGaAs,

17. (Original) The DHBT of claim 15, said insulative portion of the sub-collector including implanted ions and associated trapped conductors.

18-32. (Cancelled)

33. (Currently Amended) A heterojunction bipolar transistor (HBT), comprising:

successive emitter, base and collector layers,
an InP sub-collector layer, and

a thermally conductive InGaAs contact layer between said collector and sub-collector layers,

wherein said contact and sub-collector layers extend lateral to said collector layer.

- 34. (Previously Presented) The HBT of claim 33, said contact layer having a thickness not greater than about 500 Angstroms.
- 35. (Previously Presented) The HBT of claim 34, said contact having a thickness in the approximate range of 100-200 Angstroms.
 - 36. (Cancelled).

- 37. (Currently Amended) The HBT of claim 36 33, further comprising a contact pad on said contact layer lateral to said collector layer for establishing a contact to the collector layer through the contact and sub-collector layers.
- 38. (Previously Presented) The HBT of claim 33, wherein said sub-collector layer includes a functional portion aligned with said collector layer, and an electrically insulating portion lateral to said collector layer and outside the area of said functional sub-collector portion to electrically isolate said HBT.
- 39. (Previously Presented) The HBT of claim 38, said insulating portion of the sub-collector layer including implanted ions and associated trapped conductors.
- 40. (Currently Amended) A double heterojuntion bipolar transistor (DHBT), comprising;

an InP or InAlAs emitter,

an InGaAs base,

an InP collector,

an InP sub-collector, and

an InGaAs contact layer between said collector and sub-collector which establishes, together with the sub-collector, a low resistance contact to the collector, said contact layer being thin enough to provide a substantially higher thermal conduction path between said collector and sub-collector than would bulk InGaAs,

wherein said contact layer and sub-collector extend lateral to said collector.

- 41. (Previously Presented) The DHBT of claim 40, said contact layer having a thickness not greater than about 500 Angstroms.
- 42. (Previously Presented) The DHBT of claim 41, said contact layer having a thickness in the approximate range of 100-200 Angstroms.
- 43. (Previously Presented) The DHBT of claim 40, wherein said contact layer in doped N+.

44. (Cancelled)

- 45. (Currently Amended) The DHBT of claim $44 \underline{40}$, further comprising a contact pad on said contact layer lateral to said collector.
- 46. (Currently Amended) The DHBT of claim 44 $\underline{40}$, wherein at least a portion of said sub-collector lateral to said collector is electrically insulating to electrically isolate said HBT.
- 47. (Previously Presented) The DHBT of claim 46, said insulating portion of the sub-collector including implanted ions and associated trapped conductors.